

IN THE CLAIMS

This listing of claims replaces all prior listings:

1. (Currently Amended) A Method method of manufacturing a diffusing reflector comprising the processes of:
 - preparing a substrate;
 - forming a first resin film having photosensitivity on said substrate;
 - providing a gathering of pillar-shaped bodies isolated from each other through patterning of said resin film with photolithography;
 - deforming gently said pillar-shaped bodies through a reflow;
 - forming an uneven surface layer having the maximum inclination angle of under 12° by coating with a thin layer of a second resin said gently deformed pillar-shaped bodies and;
 - covering with the second resin open flat spaces located between said isolated pillar-shaped bodies to form one concave gap between two adjacent isolated pillar-shaped bodies so that upper end portions of said two adjacent isolated pillar-shaped bodies are higher than a lower end portion of said one concave gap in the thickness direction of the diffusing reflector, thereby minimizing an occurrence of a flat surface area on said substrate; and
 - forming a metal film on said uneven surface layer,wherein,
said first resin film is patterned by straight connected lines that form a continuous polygonal pattern, said straight lines providing a gap between thereby formed polygonal pillar-shaped bodies, and
said gap having a size equal to about a minimum resolution of said photolithography.
2. (Currently Amended) The Method method of manufacturing a diffusing reflector as claimed in claim 1, wherein said maximum inclination angle is about 10° .
3. (Cancelled)

4. (Currently Amended) ~~The Method~~ method of manufacturing a diffusing reflector as claimed in claim 1, wherein said reflow process is a heat treatment under the temperature of about 220⁰C.

5. (Currently Amended) ~~The Method~~ method of manufacturing a diffusing reflector as claimed in claim 1, wherein gathering of polygonal pillar-shaped bodies isolated from each other by the divided patterning of said first resin film by said photolithography is provided.

6. (Cancelled)